#24/E Docket No. 0756-2011 10/24/02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application of)	Art Unit: 2812
Shunpei YAMAZAKI et al.)	Examiner: V. Simkovic
Serial No. 09/362,192) [CERTIFICATE OF MAILING
Filed: July 28, 1999)	I hereby certify that this correspondence is being deposited with The United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on
For: SEMICONDUCTOR DEVICE)	
HAVING SEMICONDUCTOR CIRCUIT)	
COMPRISING SEMICONDUCTOR	ا (
ELEMENT, AND METHOD FOR)	=
MANUFACTURING THE SAME)	CCH.
MANUFACTURING THE SAME AMENDMENT Honorable Commissioner of Patents		
Honorable Commissioner of Patents		$\sigma \omega =$
Washington, D.C. 20231		2002 EMTEI EMTEI

In response to the Office Action dated May 14, 2002, please amend the above-identified application as follows:

IN THE CLAIMS:

Sir:

Please cancel claims 51, 55, 59, 63 and 66 and amend claims 45, 49, 52, 56, 60 and 64 as follows:

45. (Amended) A method for manufacturing a semiconductor device comprising steps of:

providing a material for promoting crystallization to at least a part of a semiconductor film formed over a substrate;

subjecting said semiconductor film to oxygen plasma to form a gate insulating film on said semiconductor film; and

crystallizing said semiconductor film after subjecting said semiconductor film to the oxygen plasma to obtain a crystalline semiconductor film.